



T&A-109

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

T. HATTORI et al

Serial No. 10/026,973

Group Art Unit: 1756

Filed: December 27, 2001

Examiner: S. Rosasco

For: A PHOTOMASK, THE MANUFACTURING METHOD, A PATTERNING
METHOD, AND A SEMICONDUCTOR DEVICE MANUFACTURING METHOD

RECEIVED
NOV 13 2003
TC 1700

SUPPLEMENTAL REPLY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

October 15, 2003

Sir:

Please amend the above-identified application as follows,
following a Telephonic Interview with the Examiner on October
8, 2003.